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In Application of : Daniel J HOFFMAN et al

Serial No.: 10/028,922

Filing Date: 12/19/2001

Confirmation No: 2862

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Title: PLASMA REACTOR WITH OVERHEAD RF ELECTRODE TUNED TO
THE PLASMA WITH ARCING SUPPRESSION

Form PART B – FEE(S) TRANSMITTAL with instructions to pay the Issue fee for above referenced patent application is submitted via fax to the USPTO, Mail Stop : ISSUE FEES on this day, February 9, 2006. Please charge our deposit account 50-1074.